



LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>				ATTY. DOCKET NO.:		APPLICATION SERIAL NO.:	
				4717-11700		10/691, 403	
				APPLICANT:			
				Christophe MALEVILLE et al.			
				FILING DATE:		GROUP:	
				October 21, 2003		2812	


U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
gp	AA	2002/0025604A1	2/2002	Tiwari	438	118	
gp	AB	6,593,212 B1	7/2003	Kub et al.	438	458	
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FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
gp	AG	EP 0 954 014 A1	11/1999	Europe			X	
gp	AH	WO 01/15215	3/2001	PCT			X	
	AI							

OTHER REFERENCES <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>	
gp	AJ Jean-Pierre Colinge, "Silicon-On-Insulator Technology: Materials to VSLI", 2nd Edition" by, published by "Kluwer Academic Publishers", at pages 50 and 51.
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EXAMINER 	DATE CONSIDERED 4/26/05
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
GP	AA	6,362,076 B1	3/2002	Inazuki et al.	438	458		
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FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
GP	AG	FR797713 English Abstract	2/2001	France			X	
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)								
GP	AJ	Aditya Agarwal, et al., "Efficient production of silicon-on-insulator films by co-implantation of He ⁺ with H ⁺ ", Applied Physics Letters, vol. 72 (1998), pages 1086-1088.						
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EXAMINER					DATE CONSIDERED			
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